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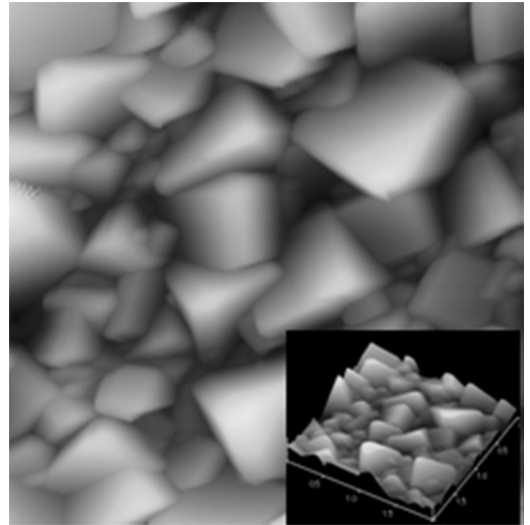
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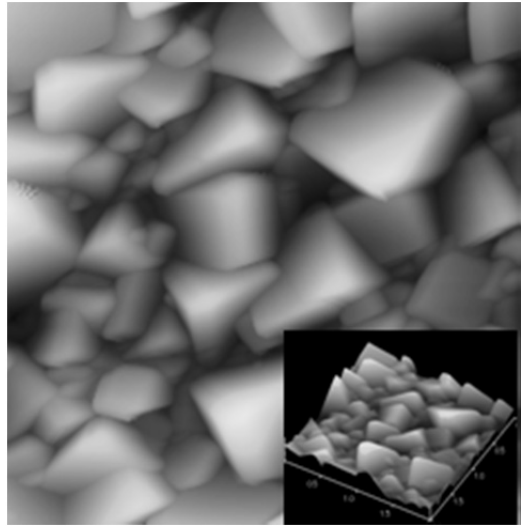
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Cover Photograph:
NaTaO₃ crystal layer fabricated on a Ta substrate
(Sayaka Suzuki, Shinshu Univ., p.68)

Cover Design: Katsuya TESHIMA